

whether explicitly stated or not, that such features or functions are present in at least the described example, whether described as an example or not, and that they can be, but are not necessarily, present in some of or all other examples. Thus 'example', 'for example' or 'may' refers to a particular instance in a class of examples. A property of the instance can be a property of only that instance or a property of the class or a property of a sub-class of the class that includes some but not all of the instances in the class.

[0107] Although embodiments of the present invention have been described in the preceding paragraphs with reference to various examples, it should be appreciated that modifications to the examples given can be made without departing from the scope of the invention as claimed.

[0108] Features described in the preceding description may be used in combinations other than the combinations explicitly described.

[0109] Although functions have been described with reference to certain features, those functions may be performable by other features whether described or not.

[0110] Although features have been described with reference to certain embodiments, those features may also be present in other embodiments whether described or not.

[0111] Whilst endeavoring in the foregoing specification to draw attention to those features of the invention believed to be of particular importance it should be understood that the Applicant claims protection in respect of any patentable feature or combination of features hereinbefore referred to and/or shown in the drawings whether or not particular emphasis has been placed thereon.

I/we claim:

1. An apparatus comprising:
 - a first sensor comprising a sensing material that is sensitive to a first parameter and a second parameter, wherein sensitivity to the first parameter changes sensitivity to the second parameter, wherein the first parameter is deformation and the second parameter is concentration of a gaseous analyte; and
 - a second sensor sensitive to at least one of the first parameter and the second parameter.
2. An apparatus as claimed in claim 1, wherein the second parameter is humidity.
3. An apparatus as claimed in claim 1, wherein the second sensor comprises the sensing material that is sensitive to the first parameter and the second parameter.
4. An apparatus comprising:
 - a first sensor comprising a sensing material that is sensitive to a first parameter and a second parameter, wherein sensitivity to the first parameter changes sensitivity to the second parameter;
 - a second sensor comprising the sensing material that is sensitive to the first parameter and the second parameter, wherein a sensitivity of the first sensor to the first parameter is different to a sensitivity of the second sensor to the first parameter.
5. An apparatus as claimed in claim 4, wherein the first parameter is deformation and the second parameter is concentration of a gaseous analyte.
6. An apparatus as claimed in claim 4, wherein the first parameter is humidity.
7. An apparatus as claimed in claim 1, wherein the sensing material is selected from the group comprising: graphene oxide, graphene, functionalised graphene, boron nitride, transition metal dichalcogenides.

8. An apparatus as claimed in claim 1, wherein the sensing material comprises a stack of two-dimensional layers of the same material.

9. (canceled)

10. An apparatus as claimed in claim 1, wherein, for a range of values of the second parameter, a sensitivity of the first sensor to the first parameter is different to a sensitivity of the second sensor to the first parameter and wherein, for a range of values of the first parameter, a sensitivity of the first sensor to the second parameter is different to a sensitivity of the second sensor to the second parameter.

11. (canceled)

12. (canceled)

13. (canceled)

14. (canceled)

15. (canceled)

16. (canceled)

17. (canceled)

18. (canceled)

19. (canceled)

20. An apparatus as claimed in claim 1, wherein a sensitivity of the first and/or second sensor is selectively controlled by: selectively suppressing sensitivity to deformation but not gaseous analyte ingress by using a physically attached coating that is permeable; or

selectively suppressing sensitivity to gaseous analyte ingress but not deformation by using an unattached impermeable coating; or

maintaining a constant gaseous analyte concentration using a seal; or

maintaining a constant deformation.

21. (canceled)

22. (canceled)

23. (canceled)

24. An apparatus as claimed in claim 1, wherein a sensitivity of the first and/or second sensor is differentially controlled by using a different thickness of sensing material in the first and second sensors or using different sensing material in the first and second sensors.

25. (canceled)

26. An apparatus as claimed in claim 1, wherein the sensing material in the first and second sensors both comprises graphene oxide but the material of one of the first and second sensors comprises one or more functional groups absent from the material of the other one of the first and second sensors.

27. An apparatus as claimed in claim 1, comprising a flexible substrate.

28. An apparatus as claimed in claim 1, comprising temperature compensation circuitry.

29. (canceled)

30. A method comprising:

processing an output from a first sensor comprising a sensing material that is sensitive to a first parameter and a second parameter, wherein sensitivity to the first parameter changes sensitivity to the second parameter, wherein the first parameter is deformation and the second parameter is concentration of a gaseous analyte; and processing an output from a second sensor sensitive to at least one of the first parameter and the second parameter.

31. A method as claimed in claim 30, wherein the second sensor comprises the sensing material that is sensitive to the first parameter and the second parameter.